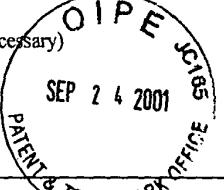


Form PTO-1449 (REV. 8-83)	US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 110157.98	APPLICATION NO. 09/779,686
INFORMATION DISCLOSURE STATEMENT			
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U.S. PATENT DOCUMENTS						
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
AM		3,538,828	11-1970	GENOVESE		
AM		4,747,678	5-1998	SHAFER et al.		
AM		4,748,478	5-1988	SUWA et al.		
AM		4,749,867	6-1988	MATSUSHITA et al.		
AM		4,822,975	4-1989	TORIGOE		
AM		4,924,257	5-1990	JAIN		
AM		5,004,348	4-1991	MAGOME		
AM		5,187,519	2-1993	TAKABAYASHI et al.		
AM		5,227,839	7-1993	ALLEN		
AM		5,281,996	1-1994	BRUNING et al.		
AM		5,506,684	4-1996	OTA et al.		
AM		5,767,948	6-1998	LOOPSTRA et al.		
AM		5,796,469	8-1998	EBINUMA		

FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
AM		JP A 4-196513 (w/abstract)	7-1992	JAPAN		
AM		JP A 63-128713	6-1988	JAPAN		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)						
EXAMINER		Buckley et al., "Step and scan: A systems overview of a new lithography tool", SPIE Vol. 1088 Optical/Laser				
		Microlithography II (1989), p. 424-433.				

EXAMINER	Alan Mathews	DATE CONSIDERED
9-18-2002		
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